Progress in the Development of a High Current H+ Ion Source for Cyclotron

Haruhiko Etoh1, Moriaki Onai2, Yasushi Aoki1, Hitoshi Mitsubori1, Yoshihiko Arakawa1, Takanori Kato1, Junji Sakuraba1, Toshinori Mitsumoto1, Satoru Yajima1, Takanori Shibata2, Takashi Yamamoto2, Akiyoshi Hatayama2, and Yoshikazu Okumura3

1Sumitomo Heavy Industries, Ltd., ThinkPark Tower, 1-1 Osaki 2-chome, Shinagawa-ku, Tokyo 141-6025, Japan
2Graduate School of Science and Technology, Keio University, 3-14-1 Hiyoshi, Yokohama 223-8522, Japan
3Fusion Research and Development Directorate, Japan Atomic Energy Agency, 2-166 Obuchi-Aza, Omotedate, Rokkasho-mura, Kamikita-gun, Aomori 039-3212, Japan

A multi-cusp DC H+ ion source has been developed for cyclotrons. In the Cs-free operation, 15 mA of H+ was obtained by increasing the magnetic filter field. To get more understanding of the relationship between H+ production and magnetic field configuration, a numerical analysis of electron energy distribution function (EEDF) has been studied. As the first results of the analysis, decreasing EEDF was observed at magnetic filter field region. And a new ion source has been designed to produce an H+ of 20 mA. The design of this source is changed to improve the source performance especially in the Cs-seeded operation.

1. Introduction

A multi-cusp DC H+ ion source for medical cyclotron has been developed. In the Cs-free operation, H+ beam of 10 mA was obtained stably at an arc power of 3 kW. By increasing the magnetic filter field strength, the saturation of the H+ current at a high arc power was improved and the maximum peak current reached 15 mA at an arc power of 6.6 kW. In the Cs-seeded operation, H+ current reached 16 mA at a lower arc power of 2.8 kW, a low extracted electron current and a low gas flow rate [1]. To get more understanding the relationship between H+ production and magnetic field configuration, a numerical analysis of electron energy distribution function (EEDF) has been studied [2]. Further improvement to enhance the beam current is in progress, a new source has been designed to achieve the next goal of producing an H+ 20 mA. In this paper, the first results of the numerical analysis on the existing source and the concepts for the design of the new ion source are presented.

2. Numerical Simulation on Existing Source

2.1 Ion Source Structure

The source consists of a cylindrical plasma chamber, multi-cusp permanent magnets and an extraction system constructed by a plasma electrode (PE), an extraction electrode (EE) and a grounded electrode (GE). Dipole magnets are located near the extraction region of the plasma chamber to produce magnetic filter field which prevents high temperature electrons from entering into the H+ production region. The EE has a pair of dipole magnets which remove electrons from H+ beam trajectory. The internal diameter and length of the plasma chamber are 100 mm and 150 mm respectively. The diameter of the PE’s aperture is 13 mm. There are two arch shape tungsten filaments to generate plasma by arc discharge. The more details of the source are shown in the previous report [1].

2.1 EEDF Analysis

In Cs-free operation, H+ ions are mainly produced by volume production via dissociative attachment process between vibrationally excited hydrogen molecules and low temperature electrons [3]. Magnetic filter field has a role to keep electron temperature as low as few electron volts in H+ production region [4]. The understanding of the relationship between H+ production and magnetic field strength is important to optimize magnetic field arrangements, so a numerical analysis on this problem has been studied.

In order to calculate the EEDF, numerical simulation code, “KEIO-MARC” [5] has been applied. In the KEIO-MARC code, equations of motion for electrons are solved by the leap-frog
method [6]. Coulomb collision process between electrons is modeled by “binary-collision” [7] and collision between electrons and hydrogen species are treated “null-collision” method [8]. In the simulation, the model of the ion source is based on the real source dimension and the magnets configuration. Figure 1 shows the results of EEDF at an arc power of 2240 kW. It is observed that the number of high energy electrons is reduced by magnetic filter field in the extraction region. This result gives qualitative agreement with the realistic source characteristic. The calculations for different magnetic filter field strengths are underway to study the EEDF dependence of the magnetic field.

Additional magnets are arranged radially near the tapered-shape PE to enhance plasma confinement and the filter field strength. Figure 2(b) shows the configuration of the source with the tapered-shape PE and the additional magnets.

4. Conclusion
The relationship between H⁻ production and magnetic field configuration has been studied by the numerical simulation. The first results of simulation of EEDF showed the effect of magnetic filter field on the electrons.

A new 20 mA H⁻ source has been designed. Two types of PE have been designed to be able to control the temperature of their surface and study the effect of the difference in the PE shape. The design has also a better maintainability. These configurations will be tested and optimized near future.

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References